

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Heng Liu

Title: Chemical Vapor Deposition Reactor

Application No.: 10/621,049

Filing Date: July 15, 2003

Examiner: Ram N. Kackar

Group Art Unit: 1763

Docket No.: M-15626 US

Confirmation No.: 8846

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Irvine, California  
June 28, 2005**Via Facsimile to (703) 872-9306**Mail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450**PETITION FOR EXTENSION OF TIME**

Dear Sir:

Applicants respectfully petition for a three-month extension of time within which to respond to the Office Action mailed December 29, 2004, such extension allowing Applicants until June 29, 2005 to respond.


Please charge the amount of \$510.00 (for a small entity) as set forth in the accompanying Transmittal Letter.

**Certification of Facsimile Transmission**

I hereby certify that this paper is being facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.

  
Monique M. ButlerJune 28, 2005  
Date of Signature

Respectfully submitted,

  
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